ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

HIGH PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submision Type: Information Disclosure

Statement

Application Number:

10/680783

EFS ID: 107958

Server Response:

Confirmation Code	Message
ISVR1	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
ICON1	5859
USPTOEFSNot	Eer assistance with e-filing a patent application, contact the Patent Electronic Business Center: Toll-Free Number:1(866) 217-9197 Website: http://www.uspto.gov/ebc/

First Named Applicant: William Jones

Attorney Docket Number:

Timestamp: 2006-07-20 18:31:24 EDT

From: us

File Listing:

Doc. Name	File Name	Size (Bytes)	Date
			Produced
			(yyyymmdd)
us-ids	SSI04001-usidst.xml	4850	2006-07-20
us-ids	us-ids.dtd	7763	2006-07-20
us-ids	us-ids.xsl	12026	2006-07-20
package-data	SSI04001-pkda.xml	1706	2006-07-20
package-data	package-data.dtd	27025	2006-07-20
package-data	us-package-data.xsl	19263	2006-07-20
	Total files size	72633	

Message Digest: 69e236734151399007c2301a828513280e525066

Digital Certificate Holder

Name:

cn=Thomas B.

Haverstock,ou=Registered Attorneys,ou=Patent and

Trademark

Office,ou=Department of

Commerce,o=U.S. Government,c=US